

INFORMATION DISCLOSURE CITATION IN AN APPLICATION		ATTY. DOCKET NO. 52352-767	SERIAL NO. <i>09/826078</i>			
(PTO-1449)		APPLICANT CHRISTY MEI-CHU WOO, ET AL.	<i>J1002/826078 PRO 10/05/04</i>			
		FILING DATE April 5, 2001	GROUP <i>1765</i>			
U.S. PATENT DOCUMENTS						
EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE
FOREIGN PATENT DOCUMENTS						
EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	Translation
						Yes
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)						
<i>40</i>	YAOZHI HU AND SING PIN TAY, "SPECTROSCOPIC ELLIPSOMETRY INVESTIGATION OF NICKEL SILICIDE FORMATION BY RAPID PROCESS", J.VAX.SCI. TECHNOL. A 16(3) MAY/JUN 1998, PP. 1820-1824. ✓					
<i>40</i>	TOYOTA MORIMOTO, TATSUYA OHGURO, HISAYO SASAKI MOMOSE, TOSHIHIKO IINUMA, IWAO KUNISHIMA, KYOICHI SUGURO, ICHIRO KATKABE, HIROOMI NAKAJIMA, MASAKATSU TSUCHIAKI, MIZUKI ONO, YASUHIRO KATSUMATA, AND HIROSHI IWAI, "SELF-ALIGNED NICKEL-MONO-SILICIDE TECHNOLOGY FOR HIGH SPEED DEEP SUBMICROMETER LOGIC CMOS ULSI", IEEE TRANSACTIONS ON ELECTRIC DEVICES, VOL. 42, NO. 5, MAY 1995. ✓					
<i>40</i>	J. CHEN, J.P. COLINGE, D. FLANDRE, R. GILLON, J.P. RASKIN, AND D. VANHOENACKER, "COMPARISON OF TiSi ₂ , CoSi ₂ , AND NiSi FOR THIN-FILM SILICON-ON-INSULATOR APPLICATIONS, J.ELECTROCHEM SOC., VOL. 144, No. 7, JULY 1997 ✓					
<i>40</i>	T. OHGURO, S. NAKAMURA, E. MORIFUJI, M. ONO, T. YOSHITOMI, M. SAITO, AND H. IWAI, "NITROGEN-DOPED NICKEL MONOSILICIDE TECHNIQUE FOR DEEP SBUMICRON CMOS SALICIDE", ULSI RESEARCH LABORATORIES, PP. 453-456 ✓					
<i>40</i>	STANLEY WOLF AND RICHARD N. TAUBER, "SILICON PROCESSING FOR THE VLSI ERA VOLUME: 1 PROCESS TECHNOLOGY", 1986 PP. 329-406. ✓					
EXAMINER	<i>40</i>		DATE CONSIDERED <i>5/28/02</i>			

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.